

25/08/03
2003054384

(12) INTERNATIONAL APPLICATION PUBLISHED UNDER THE PATENT COOPERATION TREATY (PCT)

(19) World Intellectual Property Organization
International Bureau



(43) International Publication Date
17 July 2003 (17.07.2003)

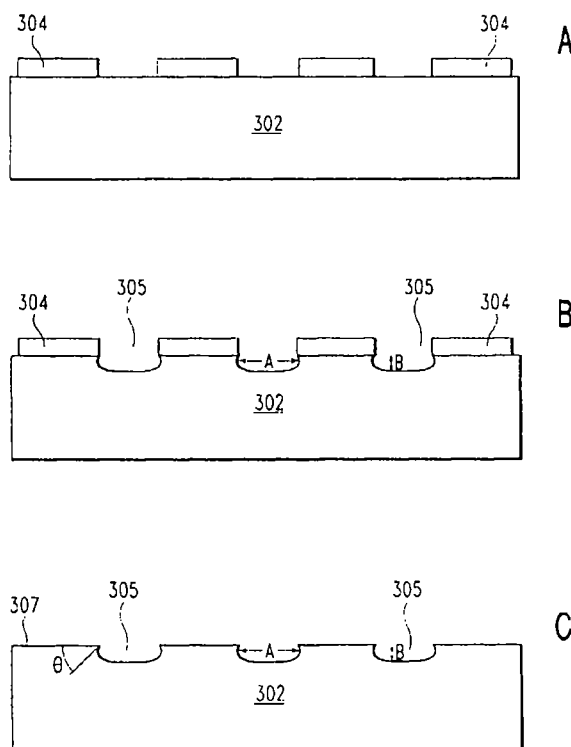
PCT

(10) International Publication Number
WO 03/057647 A1

- (51) International Patent Classification⁷: **C04B 41/91**, 41/88, 41/90, B23K 26/40, C23C 14/50, H01L 21/00
- (21) International Application Number: PCT/US02/37358
- (22) International Filing Date:
20 November 2002 (20.11.2002)
- (25) Filing Language: English
- (26) Publication Language: English
- (30) Priority Data:
10/027,683 21 December 2001 (21.12.2001) US
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- (81) Designated States (*national*): CN, JP, KR, SG.
- (84) Designated States (*regional*): European patent (AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, IE, IT, LU, MC, NL, PT, SE, SK, TR).
- Published:
— with international search report

[Continued on next page]

(54) Title: METHODS OF ROUGHENING A CERAMIC SURFACE



(57) Abstract: Disclosed herein is a method of roughening a ceramic surface by forming mechanical interlocks in the ceramic surface by a chemical etching process, a thermal etching process, or a laser micromachining process. Also disclosed herein are components for use in semiconductor processing chambers (in particular, a deposition ring for use in a PVD chamber) which have at least one ceramic surface having mechanical interlocks formed therein by chemical etching, or laser micromachining. Ceramic surfaces which have been roughened according to the chemical etching, thermal etching, or laser micromachining process of the invention are less brittle and damaged than ceramic surfaces which are roughened using conventional grit blasting techniques. The method of the invention results in a roughened ceramic surface which provides good adherence to an overlying sacrificial layer (such as aluminium).

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— *before the expiration of the time limit for amending the claims and to be republished in the event of receipt of amendments*

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